

09/807902

Rec'd PCT/PTO 19 APR 2001

Docket No.: 50212-211

3A
PATENT
9/5/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenichi ARIMURA, et al.

Serial No.:

Group Art Unit:

Filed: April 19, 2001

Examiner:

For: WAFER SUPPORT IN SEMICONDUCTOR PRODUCTION APPARATUS

PRELIMINARY AMENDMENT

Commissioner for Patents
Washington, DC 20231

Sir:

Prior to examination of the above-referenced application, please amend the application as follows:

IN THE CLAIMS:

Please amend claim 3 as follows:

3. A semiconductor production apparatus according to claim 1 [or 2], wherein (said depression) has an elongated form extending in a radial direction of said susceptor.